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Certificate

It is here by certified that the paper ID : IJRASET42825, entitled

Synthesis of SiC films by Atmospheric Pressure Chemical Vapor Deposition using Dimethylisopropylsilane Polymeric Precursor

by

Rajesh Das

after review is found suitable and has been published in Volume 10, Issue V, May 2022

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Good luck for your future endeavors

Editor in Chief, iJRASET